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High-k Dielectric FinFETs

for lonic and Biological Sensing Integrated Circuits¹

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FinFET: State-of-the-art Nanoelectronics

Despite the SiNW great potential has largely been proved, their integration with CMOS Integrated Circuits is still a challenge. Commonly, SiNWs are designed with rather large width and reduced thickness (Ribbon) and high supply voltages are applied, especially at the back-gate. In this work, we propose *n-channel fully-depleted FinFETs* (Fin Field Effect Transistor) featuring an HfO₂ gate oxide for optimized sensing measurements, toward Sensing ICs. V,g

Si-Bulk FinFETs: Technology Development

The FinFETs have been fabricated on Si-Bulk by top-down approach. Using Si₃N₄ spacers and wet oxidation, it is possible to detach and insulate the FinFETs from the Si-Bulk. The main features are:

- Substrate: p-type Si-Bulk
- Solution Total number of masks: 7, 3 virtual and 4 Chromium
- $Si_{3}N_{4}$ spacer technology for local bulk insulation





Especially upon scaling, FinFETs:

- Provide high channel control
- Less electrical degradation
- The use of back-gate is not necessary Ribbon
- Steep Subthreshold Slope

FinFET are expected to be optimal sensors because they are excellent devices!



FinFETs as pH Sensors

The FinFET sensors with HfO₂ as sensing gate, have been The liquid characterized in a liquid environment. potential is controlled by a flow through Ag/AgCl reference electrode which can be swept or kept fixed.

Main achievements:



Xel

words Microfluidic platform Label-Free FET FinFET on Si-Bulk High-k gate oxide CMOS compatible Low power Full pH response High long-term stability



- Critical steps:
- E-beam lithography for sub 20 nm features
- Section Wet oxidation of Si-Bulk
- Sesistant SU-8 coverage for liquid environment



35 nm

Fin width

А-----В А-----В

iquid gate. SU-8 openings

n-channel









Simplified process flow: fin cross sections





AlSi



- \bigcirc Full pH response: $\Delta V_{th} = 57 \text{ mV/pH}$
- Constant pH response, independent of salts
- High readout sensitivity: S_{out}=60%
- High Accuracy: 0.013 pH
- \odot Low power consumption: P \approx 10 nW



FinFETs as pH sensors: (a)I_d (V_{ref}) transfer characteristic for a metal (right Y-axis) and liquid gate (left Y-axis) FinFET, for 3 < pH < 10 with the inset showing the curve shift V_{tb}; (b) V_{tb}(pH), extracted at I_d = I_{tb} = 2nA; (c) I_d, for a FinFET sensor during a time period of 25 minutes for 3 < pH < 8 at V_{ref} = 1.5 V.

p-type

pН

3→4

FinFET long-term stability measurement over 4.5 days: (a) V_{th} for equal single-wire FinFET sensors at different die locations and constant pH = 6; (b) result of the subtraction of the data set of V_{th} for the devices D3 - D4; (c) V_{th} for different multiwire FinFET sensors at constant pH = 6.

HfO₂ MOSCAP Characterization

- The intrinsic sensitivity is always given by the gate oxide proporties in contact with liquid;
- HfO₂ as gate oxide can provide a pH response up to the Nernst limit;
- HfO₂ fully satisfies the CMOS scaling process constraints;

Sensing Common Source Amplifier

A simple architecture with one FinFET connected as load and another one as driving sensor can provide a readout gain of 6.3 with a ΔV_{th} readout of 175 mV/pH and a linear voltage-to-voltage input-output correlation. v_{∞}



TEM image (Cime, EPFL) of a Si-HfO₂-Al stack with Interfacial layer; TEM image (Cime, EPFL) of a Si-SiO₂-HfO₂-Al stack with Interfacial C-V measurements performed by MOSCAPs (bottom right inset). layer; C-V measurements performed by MOSCAP (no hysteresis).

Only growing thermal SiO, between Si and HfO, we can get rid of uncontrolled IL; Removing the IL achieves the complete suppression of hysteresis.



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